

## Elettra Sincrotrone Trieste



## Scanning photoemission imaging and spectro-microscopy: a direct approach to spatially resolved XPS

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## Photoelectron Spectroscopy – Material & Pressure Gaps



XPS = X-ray Photoelectron Spectroscopy

ESCA = Electron Spectroscopy for Chemical Analysis

```
BE = hv - KE - \Phi_s
```





## **Photoemission spectromicroscopy**



https://www.elettra.eu/elettra-beamlines/escamicroscopy.html



## Scanning PhotoElectron Microscopy (SPEM)

#### Avarage informations from ALL the illuminated part of the sample



### SMALL X-ray PROBE Move the X-ray

# PROBE across the sample



#### **Spatial resolution**

Smaller is the probe higher is the spatial resolution

https://www.elettra.eu/elettra-beamlines/escamicroscopy.html



## Synchrotron beam focusing

Synchrotron beam  $\rightarrow$  Partially coherent



https://www.elettra.eu/elettra-beamlines/escamicroscopy.html



## **ESCAmicroscopy - SPEM optics**



https://www.elettra.eu/elettra-beamlines/escamicroscopy.html



## **ESCAmicroscopy – SPEM sample stage**



#### https://www.elettra.eu/elettra-beamlines/escamicroscopy.html



## ESCAmicroscopy – Scanning PhotoElectron Microscopy (SPEM)



https://www.elettra.eu/elettra-beamlines/escamicroscopy.html



## **SPEM layout and performance**



#### **SPEM** actual performances



https://www.elettra.trieste.it/elettra-beamlines/escamicroscopy.html

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Hemispherical



## **SPEM experiments: main topics**

Nanostructures/devices characterization

- MCNTs mass transport and reactivity
- e-noses
- Size dependent electronic properties of semiconductors
- Growth mechanism

Electrochemistry/SOFC

- Electrochemical stability of materials
- Corrosion
- Mass Transport

Nanocomposite materials

- Sample preparation
- Ageing

Catalysis

- 'Material' gap: from model single-crystal metal catalysts to supported metal nano-particles.
- In situ PLD particle deposition



## Indium Zinc Oxide Pyramids with Pinholes and Nanopipes (in collaboration with A. Cremades – Uni

**Complutense Madrid – Spain)** 

Micropyramids of zinc-doped indium oxide grown by thermal treatments of compacted InN and ZnO powders at temperatures between 700 and 900 C under argon flow.





**SPEM** reveals the heterogeneous distribution of In and Zn



16 µm

Javier Bartolomé et al., J. Phys. Chem. C, 2011, 115 (16), pp 8354–8360





## **Gas phase oxidation of MCNT**



#### A. Barinov et al. Adv. Mat. 21 (19) 1 (2009)

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## Doping by nitrogen ion implantation of suspended graphene flakes



(a) (b) 12 5' N total 10 (% concentration (at. 15' N, Intensity (arb. units) RI 6 Nitrogen ( 250°0 430°C 395 5' N2\* 15' N,\* 250°C 405 400 430° Binding Energy (eV) RT

Control of nitrogen component by heating the sample to mid-temperatures (430°C)

Difference between supported and suspended graphene (role of the substrate) (Supported: unwanted disorder due to recoil and backscattering)

#### M. Scardamaglia et al., Carbon 73, 371 (2014)



## SOFC operating under working condition







#### collaborations:

M. Backhaus - Corning Inc. (USA)

- B. Luerssen University of Giessen (Germany)
- B. Bozzini Università del Salento, Lecce (Italy)

Bocchetta et al. ACS Appl. Mater. Interfaces. 6 (2014) 19621– 19629

Bozzini et all. Electrochem Comm, Vol. 24, pp.104-107 (2012) Bozzini et all. ChemSusChem, Vol. 4 - 8, pp. 1099-1103 (2011) Backhaus et al. Advances in Solid Oxide Fuel Cells III 28 (4), 2007.

Backhaus et al. Solid State Ionics 179 (2008) 891–895 , M. Valov et al. *Phys. Chem. Chem. Phys.*, 2011, 13, 3394-3410 Ecc...

#### Strongly constraining experimental setup



Real samples
High T = 650-700°C
P=1x10<sup>-6</sup> mbar
Applied potentials

-2V<U<+2V</li>

Surface sensitive technique
High lateral resolution



# ESCAmicroscopy – electrochemical SPEM characterizzation

#### Catalyst stability in acidic solution under oxygen reduction

#### Pyrolized Co/PPy on Graphite

Aging: Voltammetric cycle in O<sub>2</sub>-saturated 0.5M H<sub>2</sub>SO<sub>4</sub>



Bocchetta et al. ACS Appl. Mater. Interfaces. 6 (2014) 19621–19629



## ESCAmicroscopy – electrochemical SPEM characterizzation

(a)





Bocchetta et al. ACS Appl. Mater. Interfaces. 6 (2014) 19621–19629



## ESCAmicroscopy – Self Driven Single Chamber SOFC *In operando* condition



B. Bozzini et al. Scientific Report 3, 2848, 2013



## ESCAmicroscopy – Self Driven Single Chamber SOFC *In operando* condition



self-driven activity of electrochemical cell starts

Chemical reduction Ni<sup>2+</sup>+H<sub>2</sub>→Ni+2H<sup>+</sup>





## ESCAmicroscopy – Self Driven Single Chamber SOFC *In operando* condition



Simultaneously mapping the local chemical state and the local electrochemical activities



## **Near ambient pressure XPS**

- short mean free path of electrons in a gas phase
- High voltage components to detect the single electron

## Confine the high pressure at the sample

State of the art approach:

Electron analyzers coupled with sophisticated differentially pumped lenses



## Ambient pressure SPEM: • X-ray optics • Sample Stage • Differentially pumped analyzer • Challenging technical solutions



## Environmental cell using graphene oxide windows

(in collaboration with A. Kolmakov – Souther Illinois Uni. - USA)



## Graphene oxide windows for *in situ* environmental cell photoelectron spectroscopy

Andrei Kolmakov<sup>1\*</sup>, Dmitriy A. Dikin<sup>2</sup>, Laura J. Cote<sup>2</sup>, Jiaxing Huang<sup>2</sup>, Majid Kazemian Abyaneh<sup>3</sup>, Matteo Amati<sup>3</sup>, Luca Gregoratti<sup>3</sup>, Sebastian Günther<sup>4</sup> and Maya Kiskinova<sup>3</sup>

- low-cost, single-use environmental cells
- compatible with XPS and Auger instruments







#### A.Kolmakov et al. Nature Nanotechnology 6, 651–657 (2011) J.Kraus et al. Nanoscale, 2014, 6, 14394



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## **Dynamic high pressure XPS**



### **Pulsed supersonic beam**

High freq pulsed dosing valve + nozzle
UHV compatible system
Low cost
Compact design
Can be used in any SPEM/XPS/Auger system



 $t_{AP} \sim 3 \text{ ms}$  $f_{AP} = 350 \text{ mHz}$  $P_{valve} = 3.5 \text{ bar}$ 





#### M Amati et al. Journal of Instrumentation, Vol. 8 - 05, pp. T05001 (2013)

## **Dynamic high pressure XPS**

#### Si oxidation (530°C) STATIC <-> Dynamic HP comparison

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#### Equivalent Static Pressure 10<sup>-3</sup> - 10<sup>-2</sup> mbar

#### Single Shot MAX pressure ~ 10 mbar



M Amati et al. Journal of Instrumentation, Vol. 8 - 05, pp. T05001 (2013) Doh et al. ChemElectroChem Vol. 1 - 1, pp. 180-186 (2014)







## **Radiation Damage**

#### PEDOT – PSS film

- Conventional XPS and OSA spectra are similar
- Even the faster map show damage







## Thank you!





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